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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/762,526 Group Art Unit: 1763
Filing Date: January 23, 2004 Examiner: Jeffrie R. LUND
Applicant: Chang Won CHOI et al.
Title: WAFER EDGE ETCHING APPARATUS AND METHOD
Attorney Docket: 2557-000177/US

Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314
Mail Stop Amendment

November 6, 2006

AMENDMENT

Sir:

In response to the Office Action mailed June 6, 2006, the due date having been extended two (2) months to November 6, 2006, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

Amendments to the Claims begin on page 2 of this Amendment.

Remarks begin on page 9 of this Amendment.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
Total	44	-	44	=	0
Independent	6	-	6	=	0

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